

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of:

Hitoshi YAMADA, et al.

Serial No.

Group Art Unit:

Confirmation No.

Filed: February 13, 2002

Examiner:

For: GAS DISCHARGE TUBE AND METHOD FOR FORMING ELECTRON EMISSION  
LAYER IN GAS DISCHARGE TUBE

**PRELIMINARY AMENDMENT**

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Before examination of the above-identified application, please amend the application as follows:

**IN THE CLAIMS:**

Please AMEND the pending claims in accordance with the following:

4. A method for manufacturing a gas discharge tube as claimed in Claim 1, in which the electron emission film is produced by the steps of:

injecting a coating solution at a predetermined amount from one opening of a tube having an opening in each of both ends thereof, said coating solution containing an organic metal compound that turns into an inorganic metal compound having an electron emission ability by a burning process;

forming a coating film on the entire inner wall of the tube by causing the coating solution to go along the inner wall of the tube while entirely sealing the opening of the tube; and

burning the coating film to form an electron emission film on the entire inner wall of the tube.